

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Reissue Patent Application:

Applicant : Gurtej S. Sandhu
Assignee: : Micron Technology, Inc.
Filed : December 28, 2001
For : METHOD AND APPARATUS FOR ENDPOINTING MECHANICAL AND
CHEMICAL-MECHANICAL POLISHING OF SUBSTRATES
Docket No. : 500042.02

Corresponding Issued U.S. Patent:

Patent No. : 6,007,408
Issued : December 28, 1999
Application No. : 08/917,665
Filing Date : August 21, 1997
Examiner : George Nguyen
Art Unit : 3723

BOX REISSUE
Commissioner for Patents
Washington, DC 20231

PRELIMINARY AMENDMENT

Sir:

Please accept the request for a reissue of U.S. Patent No. 6,007,408, filed herewith. Prior to conducting the examination of the reissue claims, please amend the reissue application as follows:

Please add the following new claims 14-49:

-- 14. The method of claim 1, further comprising sensing the pH of the byproducts.

15. The method of claim 1, further comprising sensing the conductivity of the byproducts.